

# Mark Pallay

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/7259208/publications.pdf>

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11  
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85  
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#	ARTICLE	IF	CITATIONS
1	Towards a high bias voltage MEMS filter using electrostatic levitation. Mechanical Systems and Signal Processing, 2021, 150, 107250.	8.0	12
2	Feasibility study of a micro-electro-mechanical-systems threshold-pressure sensor based on parametric resonance: experimental and theoretical investigations. Journal of Micromechanics and Microengineering, 2021, 31, 025002.	2.6	6
3	A Tunable Electrostatic MEMS Pressure Switch. IEEE Transactions on Industrial Electronics, 2020, 67, 9833-9840.	7.9	17
4	Merging parallel-plate and levitation actuators to enable linearity and tunability in electrostatic MEMS. Journal of Applied Physics, 2019, 126, .	2.5	19
5	Pairing electrostatic levitation with triboelectric transduction for high-performance self-powered MEMS sensors and actuators. Applied Physics Letters, 2019, 115, .	3.3	14
6	Threshold Pressure Sensing Using Parametric Resonance in Electrostatic MEMS. , 2019, , .		1
7	A Combined MEMS Threshold Pressure Sensor and Switch. , 2019, , .		1
8	A parametric electrostatic resonator using repulsive force. Sensors and Actuators A: Physical, 2018, 277, 134-141.	4.1	26
9	A reliable MEMS switch using electrostatic levitation. Applied Physics Letters, 2018, 113, .	3.3	22
10	Parametrically Excited Electrostatic MEMS Cantilever Beam With Flexible Support. Journal of Vibration and Acoustics, Transactions of the ASME, 2017, 139, .	1.6	10
11	Dynamic behavior of an electrostatic MEMS resonator with repulsive actuation. Nonlinear Dynamics, 2017, 89, 1525-1538.	5.2	43